Special Issue

3D Holographic Displays

Message from the Guest Editor

The 3D holographic display is considered the ultimate display technology, as it directly reconstructs the target wavefront and provides all depth cues for human beings. Novel techniques in photonics, optoelectronics, computer science, and other fields boost the rapid development of holographic display. In 3D holographic displays, the limitation of algorithms and core modulators is the main bottleneck, which attracts a large number of scholars to break it. Accordingly, this Special Issue seeks to showcase research papers, communications, and review articles that focus on: (1) spatial light modulators and other devices, which offers more effective light manipulation or novel ways; (2) 3D holographic display systems to improve the performance on display quality, viewing angle, field of view, etc.; (3) algorithms for hologram generation, including fast generation based on mathematical operation, neural network methods, algorithms for high-quality reconstruction, hologram generation for better rendering effect or occlusion; and (4) holographic near eye display and head up display, and other improvement on 3D holographic displays.

Guest Editor

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